

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449B/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Application Number	10/826,007
		Filing Date	04/16/2004
		First Named Inventor	Hongxing TANG et al.
		Group Art Unit	2855
		Examiner Name	Unassigned
		Attorney Docket Number	049411-0268
(use as many sheets as necessary)			
Sheet	1	of	1

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
JPB	A1	2003/0062193	A1	THAYSEN et al.	04/03/2003	
	A2	2003/0089182	A1	THAYSEN et al.	05/15/2003	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Documents	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴				

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ⁶
JPB	A3	HARLEY et al., "High-Sensitivity Piezoresistive Cantilevers Under 1000 A Thick," Physics Letters, Vol. 75, No. 2, American Institute of Physics, July 12, 1999, pp. 289-291.	
	A4	HARLEY et al., "1/F Noise Consideration for The Design and Process Optimization of Piezoresistive Cantilevers," Journal of Microelectromechanical Systems, Vol. 9, No. 2, IEEE, June 2, 2000, pp. 226-235.	
	A5	HUTTER et al., "Calibration of Atomic-Force Microscope Tips," Rev. Sci. Instrum., Vol. 64, No. 7, American Institute of Physics, July 1993, pp. 1868-1873.	
	A6	KUCZYNSKI, "Effect of Elastic Strain on The Electrical Resistance of Metals," Physical Review, Vol. 94, No. 1, April 1, 1954, pp. 61-64.	
	A7	LI et al., "Thin Gold Film Strain Gauges," J. Vac. Sci. Technol., Vol. 12, No. 3, American Vacuum Society, May 1994, pp. 813-819.	
	A8	PARKER et al., "Electrical Resistance-Strain Characteristics of Thin Evaporated Metal Films," Journal of Applied Physics, Vol. 34, No. 9, September 1963, pp. 2700-2708.	
	A9	Physics Web, "Nanoelectromechanical Systems Face The Future," Physics World Magazine, Vol. 14, Issue 2, February 2001, http://physicsweb.org/article/world/14/2/8 .	
	A10	REID et al., "6-MHz 2-N/m Piezoresistive Atomic-Force-Microscope Cantilevers With INCISIVE Tips," Journal of Microelectromechanical Systems, Vol. 6, No. 4, IEEE, December 4, 1997, pp. 294-302.	
	A11	THAYSEN et al., "Polymer-Based Stress Sensor With Integrated Readout," Journal of Physics D: Applied Physics, Vol. 35, Institute of Physics Publishing Ltd., 2002, pp. 2698-2703.	
	A12	TORTONESE et al., "Atomic Resolution With An Atomic Force Microscope Using Piezoresistive Detection," Applied Physics Letters, Vol. 62, No. 8, American Institute of Physics, February 22, 1993, pp. 834-836.	
	A13	YANG et al., "Monocrystalline Silicon Carbide Nanoelectromechanical Systems," Applied Physics Letters, Vol. 78, No. 2, American Institute of Physics, January 8, 2001, pp. 162-164.	

Examiner Signature	<i>James P. Bente</i>	Date Considered	19 December 2005
--------------------	-----------------------	-----------------	------------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.